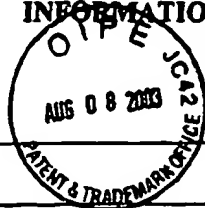


**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**



Attorney Docket Number	4641-59261
Application Number	09/881,445
Filing Date	June 13, 2001
First Named Inventor	Ushio
Art Unit	2818
Examiner Name	Not yet assigned

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
MS		4,645,349	Feb. 24, 1987	Tabata
MS		4,744,660	May 17, 1988	Noguchi <i>et al.</i>
MS		5,696, 583	Dec. 9, 1997	Yoon
MS		5,893,796	Apr. 13, 1999	Birang <i>et al.</i>
MS		5,964,643	Oct. 12, 1999	Birang <i>et al.</i>
MS		6,045,439	Apr. 4, 2000	Birang <i>et al.</i>
MS		6,280,290 B1	Aug. 28, 2001	Birang <i>et al.</i>
MS		US2001/0036805 A1	Nov. 1, 2001	Birang <i>et al.</i>
MSB		6,537,133 B1	Mar. 25, 2003	Birang <i>et al.</i>

FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
MS		56-153207 /	Nov. 27, 1981	Japan (w/English abstract)
MS		60-305 /	Jan. 5, 1985	Japan (w/English translation of relevant part)
MS		61-76904 /	April 19, 1986	Japan (corresponds to US 4,645,349)
MS		61-235708 /	Oct. 21, 1986	Japan (corresponds to US 4,744,660)
MS		63-50703 /	March 3, 1988	Japan (w/English translation of relevant part)
MS		64-57107 /	March 3, 1989	Japan (w/English translation of relevant part)
MS		6-147838 /	May 27, 1994	Japan (w/English translation)









EXAMINER
SIGNATURE:


MSB

DATE
CONSIDERED:

10-27-04

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT 		Attorney Docket Number		4641-59261
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		Art Unit		2818
		Examiner Name		Not yet assigned
		6-252113	Sept. 9, 1994	Japan (w/English translation)
		8-145631	June 7, 1996	Japan (corresponds to US 5,696,583)
		9-7985	Jan. 10, 1997	Japan (corresponds to US 6,537,133)
		EP 0824995 A1	Feb. 25, 1998	EPC
		EP 0738561 B1	Jan. 23, 2002	EPC
Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>CMP-IMC Conference</i> , pp. 23-29, Feb. 11-12, 1999		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>IMIC Journal on CMP</i> , Vol. 1, No. 1, Fall, 1999		

EXAMINER SIGNATURE: 	DATE CONSIDERED: 10-27-04
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Docket: 4641-59261

App: 09/881,445

Applicant: Ushio et al.

Filed: June 13, 2001

Art Unit: 2818

U.S. PATENT DOCUMENTS

Init.*		Number	Date	Name	Class	Sub	Filed

FOREIGN PATENT DOCUMENTS

		Number	Date	Country	Class	Sub	
<i>MM</i>		JP63-050703	3/3/98	Japan With English Abstract	—	—	
<i>MM</i>		JP64-057107	3/3/89	Japan With English Abstract	—	—	
<i>MM</i>		JP06-252113	9/9/94	Japan With English Abstract	—	—	

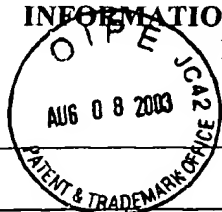
OTHER DOCUMENTS

EXAMINER: *MM*

DATE *10-27-04*

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<i>MM</i>		5,893,796	Apr. 13, 1999	Birang <i>et al.</i>
<i>MM</i>		5,964,643	Oct. 12, 1999	Birang <i>et al.</i>
<i>MM</i>		6,045,439	Apr. 4, 2000	Birang <i>et al.</i>
<i>MM</i>		6,280,290 B1	Aug. 28, 2001	Birang <i>et al.</i>
<i>MM</i>		US2001/0036805 A1	Nov. 1, 2001	Birang <i>et al.</i>
<i>MM</i>		6,537,133 B1	Mar. 25, 2003	Birang <i>et al.</i>

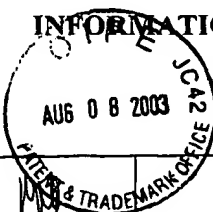







FOREIGN PATENT DOCUMENTS

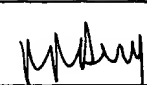
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<i>MM</i>		60-305 /	Jan. 5, 1985	Japan (w/English translation of relevant part)
<i>MM</i>		61-76904 /	April 19, 1986	Japan (corresponds to US 4,645,349)
<i>MM</i>		61-235708 /	Oct. 21, 1986	Japan (corresponds to US 4,744,660)
<i>MM</i>		63-50703 /	March 3, 1988	Japan (w/English translation of relevant part)
<i>MM</i>		64-57107 /	March 3, 1989	Japan (w/English translation of relevant part)
<i>MM</i>		6-147838 /	May 27, 1994	Japan (w/English translation)


EXAMINER
SIGNATURE: *YMM*

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT 		Attorney Docket Number		4641-59261
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		Filing Date		June 13, 2001
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		Art Unit		2818
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		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>IMIC Journal on CMP</i> , Vol. 1, No. 1, Fall, 1999		

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Docket: 4641-59261		App: (Unknown)	
				Applicant: Ushio et al.			
				Filed: June 13, 2001		Art Unit: (Unknown)	
U.S. PATENT DOCUMENTS							
Init.*		Number	Date	Name	Class	Sub	Filed
<i>MD</i>		6,102,775	8/15/00	Ushio et al.			<div style="writing-mode: vertical-rl; transform: rotate(180deg);"> 310000 U.S. PRO 09/881445 06/13/01 </div> 
FOREIGN PATENT DOCUMENTS							
		Number	Date	Country	Class	Sub	
		10311708	24.11.98	Japan (English Abstract Only)			
OTHER DOCUMENTS							
EXAMINER: <i>MD</i>				DATE: <i>10-27-04</i>			
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